

AP20 Rec'd PTO/PTO 28 JUN 2006

Sheet 1 of 1

| | | | | | | | |
|---|--|---|--|----------------------------|--|--|--|
| Form PTO-1449 (REV. 1/06) | | US Dept. of Commerce PATENT & TRADEMARK OFFICE | | ATTY DOCKET NO. 128503 | | APPLICATION NO. New U.S. Patent Application 10584771 | |
| INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) | | | | APPLICANT Isao YOKOKAWA | | FILING DATE June 28, 2006 | |
| | | | | | | GROUP 2812 | |

| U.S. PATENT DOCUMENTS | | | | | | |
|-----------------------|-------------|-----------------|------|------|--|--|
| Examiner Initials | Cite No. | Document Number | Date | Name | | |
| | | | | | | |
| | | | | | | |
| | | | | | | |
| | | | | | | |
| | | | | | | |

| FOREIGN PATENT DOCUMENTS | | | | | | |
|--------------------------|-------------|------------------|------------|---------|-----------------------------|--------------------------------|
| Examiner Initials | Cite No. | Document Number | Date | Country | With English Abstract | With English Translation |
| /CL/ | 1 | JP A 2001-217430 | 8/10/2001 | Japan | X | X |
| ↓ | 2 | JP A 2002-164520 | 6/7/2002 | Japan | X | X |
| ↓ | 3 | JP A 2002-305293 | 10/18/2002 | Japan | X | X |
| ↓ | 4 | JP A 2003-229360 | 8/15/2003 | Japan | X | X |
| ↓ | 5 | JP A 2003-229361 | 8/15/2003 | Japan | X | X |
| ↓ | 6 | JP A 2000-286413 | 10/13/2000 | Japan | X | X |
| /CL/ | 7 | JP A 11-304729 | 11/5/1999 | Japan | X | X |

| OTHER DOCUMENTS | | |
|----------------------|-------------|--|
| Examiner Initials | Cite No. | (Including Author, Title, Date, Pertinent Pages, etc.) |
| /CL/ | 8 | M. Erdmann et al, "Structural Characterization of Strained Silicon Substrates by X-Ray Diffraction and Reflectivity", Extended Abstracts of the 2003 International Conference on Solid State Devices and Material, Tokyo, pp. 290-291, 2003. |
| /CL/ | 9 | W.L. Bond, "Precision Lattice Constant Determination", Acta Crystallographica, pp. 814-818, October 10, 1960. |
| | | |
| | | |
| | | |
| | | |

| | |
|---|-------------------------------|
| EXAMINER /Cheung Lee/ | DATE CONSIDERED 11/07/2008 |
| Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | |